

Notice of References Cited

Application/Control No.

09/917,095

Applicant(s)/Patent Under
Reexamination
YAMAZAKI ET AL.

Examiner

Evan T. Pert

Art Unit

2829

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages			
	U	Z. Jian-ming, "Optimization of Glow Discharge Deposition of Amorphous Silicon Films", 1988, 20 th IEEE Photovoltaic Specialists Conference, vol. 1, pages 296-300.			
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